IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Kuei-Jen Chang

Serial No.: 09/822,749

Group Art Unit: 1763

Examiner: Mulero Luz L. Alejandro

Filed:

March 30, 2001

In Response to Office Action

Dated:

April 4, 2003

For:

Method and Apparatus for In-Situ Descum/Hot Bake/Dry

Etch Photoresist/Polyimide Layer

Attorney Docket No.: 67,200-397

Certificate of Facsimile I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Patent Office via facsimile no. (703) 672-9311 on Dune 4, 2003

REQUEST FOR RECONSIDERATION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In response to a final Office Action mailed April 4, 2003, please consider the following remarks.